

The 2nd International Student Workshop on Electrical Engineering

Date: March 11, 2010

Venue: Meijyo University, Japan

Organized and preceded by students

Organizing Chairperson:

S. Iwashita (Kyushu University, Japan)

Supported by

- Good Practice Project for Promotion of Systematic Graduate Education,
- Department of Electrical Engineering,
- Graduate School of Information Science and Electrical Engineering,
Kyushu University, Japan

Student GP Session (10) (8min+2min Q&A)

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|-------|-----|---|
| 15:15 | S-1 | A Stable Large-Volume Fluorine Negative-Ion Source for Ultrafine Etching
M Abid Imtiaz, T. Mieno
Shizuoka University, Japan |
| 15:25 | S-2 | Effects of amplitude modulation of RF discharge voltage on ion saturation current
Hiroshi Miyata, Shinya Iwashita, Yasuyuki Yamada, Kazunori Koga, Masaharu Shiratani
Kyusyu University, Japan |
| 15:35 | S-3 | Synthesis dynamics of nanoparticles produced by laser ablation of a solid target immersed in pressurized water
Wafaa Soliman, Noriharu Takada, Koichi Sasaki
Nagoya University, Japan |
| 15:45 | S-4 | XPS Analysis of Plasma-Polymer Interactions for Organic-Inorganic Hybrid Materials
Ken Cho, Kosuke Takenaka, Yuichi Setsuhara, Masaharu Shiratani, Makoto Sekine, Masaru Hori
Osaka University, Japan |

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| 15:55 | S-5 | <p>Ha emission intensity measurements of $H_2 + Ar + C_7H_8$ plasmas in H-assisted plasma CVD reactor</p> <p>Takuya nomura, Yuki Korenaga, Kazunori Koga, Masaharu Shiratani, Yuichi Setsuhara, Makoto Sekine, Masaru Hori</p> <p>Kyushu University, Japan</p> |
| 16:05 | S-6 | <p>Ar/H₂O plasma treatment of multiwall carbon nanotubes for dispersion Improvement in water</p> <p>Changlun Chen, Akihisa Ogino, Bo Liang, Masaaki Nagatsu</p> <p>Shizuoka University, Japan</p> |
| 16:15 | S-7 | <p>Deposition of n-type a-Si:H using SiH₄+PH₃ multi-hollow discharge plasma CVD</p> <p>Kenta Nakahara, Hiroshi Sato, Yuuki Kawashima, Kazunori Koga, Masaharu Shiratani</p> <p>Kyushu University, Japan</p> |
| 16:25 | S-8 | <p>Surface temperature rise of a-Si:H films during deposition in silane multi-hollow discharges</p> <p>Yuki Kawashima, Kenta Nakahara, Hiroshi Sato, William Makoto Nakamura, Kazunori Koga, Masaharu Shiratani</p> <p>Kyushu University, Japan</p> |
| 16:35 | S-9 | <p>Numerical Analysis on Heat Convection in the Synthesis of Single Walled Carbon Nanotubes by Arc Vaporization</p> <p>Guodong Tan, Tetsu Mieno</p> <p>Shizuoka University, Japan</p> |
| 16:45 | S-10 | <p>Effect of Post-Baking on Copper Adhesion to Polyimide Films Treated by High Density Microwave Plasma</p> <p>Kenji Usami, Tatsuo Ishijima, Hirotaka Toyoda, Kiyoshi Iseki, Hideo Sugai</p> <p>Nagoya University, Japan</p> |
| 19:00-20:30 | | <p>Banquet</p> |